

DOCKET NO: 265523US26PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :  
HARUHIKO FURUYA, ET AL. : EXAMINER: MALDONADO, JULIO J.  
SERIAL NO: 10/523,974 :  
FILED: FEBRUARY 8, 2005 : GROUP ART UNIT: 2823  
FOR: SEMICONDUCTOR PROCESSING :  
METHOD AND APPARATUS FOR  
PROCESSING TARGET SUBSTRATE

**RESPONSE TO RESTRICTION REQUIREMENT**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

In response to the Restriction Requirement mailed April 2, 2007, Applicants hereby elect Group I, Claims 1-17. This election is made with traverse.

It is respectfully submitted that the subject matter of all claims 1-18 is sufficiently related that a thorough search for the subject matter of any one group of claims would necessarily encompass a search for the subject matter of the remaining claims. Thus, it is respectfully submitted that the search and examination of the entire application could be performed without serious burden. MPEP §803 states that if the search and examination of an entire application can be made without serious burden, the Examiner must examine it on the merits, even though it includes claims to distinct or independent inventions.

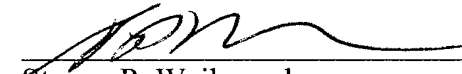
It is respectfully submitted that this policy should apply in the present application in order to avoid unnecessary delay and expense to Applicants and duplicative examination by the Patent Office.

Application No. 10/523,974  
Reply to Office Action of April 2, 2007

The Examiner is respectfully requested to reconsider and withdraw the Restriction Requirement and to examine all claims in this application.

Respectfully submitted,

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